

The PA200 was designed to be the most precise and flexible semi-automatic test solution for wafers and substrates up to 200 mm. The PA200 gives you reliable probing and precise measurements on decreasing pad and feature sizes down to the submicron range. It is ideal for failure analysis (FA), RF and mm-wave applications up to 500 GHz, as well as for opto-engineering and MEMS tests.

To ensure maximum stability and precision, the PA200 relies on precisely machined components. The use of ground slides and ball-screw drives in closed-loop positioning with glass scales produce excellent performance. Based on your application needs, you can choose between vacuum, magnetic or dedicated high-frequency probe platens.

In order to provide maximum flexibility, our modular design concept allows us to mount microscopes based on your needs. This gives you the freedom to upgrade your PA200 from a simple manual microscope stage to a fully programmable microscope with high magnification.

FEATURES / BENEFITS

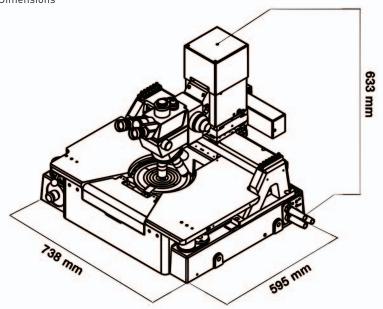
Flexibility	Ideal for FA, RF, opto-engineering and MEMS tests	
	Large number of accessories available, e.g., laser cutters, probe card holders, ShieldEnclosure™,	
	emission microscopes	
	RF tests supported by wide range of probes and calibration tools, such as calibration tools and WinCal XE™	
	calibration software	
Precision	Best position accuracy available on the market	
	Ideal for small structures even down to submicron probing	
	Highly stable mechanics	
	QuietMode™ technology for sensitive measurements	
Ease of use	Unique and easy to operate ProberBench™ Operating Environment	
	Joystick controller with color display for full prober control	
	Intuitive and ergonomic layout of system controls	



Travel range	200 mm x 200 mm
Resolution	0.5 μm
Repeatability	± 1.0 µm
Accuracy	± 1.5 μm
Planarity	8 µm
Chuck Stage Z Movement	
Travel range for non-thermal chuck	25 mm
Travel range for thermal chuck	13 mm
Resolution	0.25 µm
Repeatability	± 1.0 µm
heta Movement	
Travel range	± 6.0°
Resolution	0.0001°
Programmable Microscope Movement	
Travel range	50 mm x 50 mm
Resolution	0.25 µm
Repeatability	± 1.0 µm
Accuracy	± 2.5 µm
Access lift	130 mm
fanual Platen Movement (optional)	
Drive type	Compound knob
Coarse adjustment for non-thermal chuck	20 mm
Coarse adjustment for thermal chuck	10 mm
Contact / seperation stroke	0.4 mm linear with 1 μm repeatability
Graphical user interface	Windows based
Remote Interfaces	
PC	RS232, IEEE488, LAN, TTL, GPIB
Electronics	IEEE488, TTL, GPIB
Jtilities	
Power	115 / 230 V, 50 / 60 Hz, 600 W (maximum 150 VA)
Vacuum	Less than 200 mbar abs
Compressed air	4 bar minimum

^{*}Data, design and specification depend on individual process conditions and can vary according to equipment configurations. Not all specifications may be valid simultaneously.

Dimensions



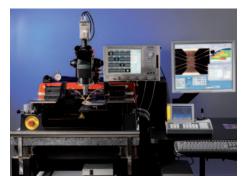
APPLICATIONS



Testing MEMS with the PA200 in a light-tight environment.



Failure analysis with the PA200 and a laser cutter.



Automated multiport on-wafer measurements with the PA200 and VNA.

© Copyright 2013 Cascade Microtech, Inc.
All rights reserved. Cascade Microtech is a registered trademark, and ProberBench, VisionModule,
CorePackage and VideoTracker are trademarks of
Cascade Microtech, Inc. All other trademarks are the property of their own respective owners.

Data subject to change without notice

PA200-DS-0913

Cascade Microtech, Inc. Corporate Headquarters

toll free: +1-800-550-3279 phone: +1-503-601-1000 email: cmi_sales@cmicro.com

Germany phone: +49-89-9090195-0 email: cmg_sales@cmicro.com

phone: +81-3-5615-5150 email: cmj_sales@cmicro.com

phone: +86-21-3330-3188 email: cmc_sales@cmicro.com

Singapore

phone: +65-6873-7482 email: cms_sales@cmicro.com

Taiwan

phone: +886-3-5722810 email: cmt_sales@cmicro.com

